


<b>LIST OF REFERENCES CITED BY APPLICANT</b> <i>(Use several sheets if necessary)</i>				ATTY. DOCKET NO.:		APPLICATION NO.:		
				4717-10100		10/784,040		
				APPLICANT:				
				Eric NEYRET et al.				
				FILING DATE:		GROUP:		
				February 20, 2004		2825		
<b>U.S. PATENT DOCUMENTS</b>								
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
ABM	AA	6,150,696	11/2000	Iwamatsu et al.	257	347		
	AB							
	AC							
	AD							
	AE							
	AF							
	AG							
	AI							
<b>FOREIGN PATENT DOCUMENTS</b>								
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
ABM	AJ	EP 1 158 581	11/2001	Europe	—	—	X	
ABM	AK	JP 7161948 (w/English Abstract)	6/1995	Japan	—	—	X	
ABM	AL	JP2000299451 (w/English Abstract)	10/2000	Japan	—	—	X	
ABM	AM	WO 01/15218 A1	11/2001	PCT	—	—	X	
ABM	AN	WO 03/005434 A2	1/2003	PCT	—	—	X	
	AO							
<b>OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)</b>								
ABM	AP	Jean-Pierre Colinge, "Silicon-On-Insulator Technology: Materials to VSLI", 2nd Edition" by, published by "Kluwer Academic Publishers", at pages 50 and 51." 1997						
	AQ							
<b>EXAMINER</b>					<b>DATE CONSIDERED</b>			
					9-16-2004			
<b>*EXAMINER:</b> Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								